Surface and Interface

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Local Valence Electronic States of SiO₂ Ultrathin Films Grown on Si(100) Studied Using Auger Photoelectron Coincidence Spectroscopy (APECS): Observation of Upward Shift of Valence-Band Maximum as a Function of SiO₂ Thickness

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Introduction

The local valence electronic states of SiO_2 ultrathin films grown on a Si(100)-2×1 surface ($SiO_2/Si(100)$) have been studied extensively because (1) in-depth understanding of the electronic properties of surfaces and interfaces from an atomic point of view is of fundamental importance in science, and (2) these films play dominant roles in metal-oxide-semiconductor field-effect transistors (MOS-FETs). Therefore we investigate the local valence electronic states of the surface of the $SiO_2/Si(100)$ ultrathin films by using $Si-L_{23}VV$ Auger electron – Si^{4+} -2p photoelectron coincidence spectroscopy ($Si-L_{23}VV$ - Si^{4+} -2p APECS, the oxidation number represents the number of oxygen bonding to Si) [1].

Results and Discussions

Figure 1 shows the Si-2p photoelectron spectrum of a SiO₂/Si(100) with a thickness of 2.8 Å (\approx 2 ML, 2.8-Å SiO₂/Si(100)). The Si-2p peaks are decomposed into the Siⁿ⁺-2p photoelectron components (n=0,1,2,3,4). The straight dashed line at +4.1 eV represents the Si⁴⁺-2p photoelectron kinetic energy (PeKE) position taken as the trigger signals for the Si- $L_{23}VV$ -Si⁴⁺-2p APECS measurements.

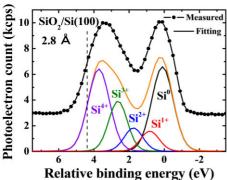


Fig. 1. Si-2*p* photoelectron spectrum of SiO_2 thermally grown on Si(100)-2×1.

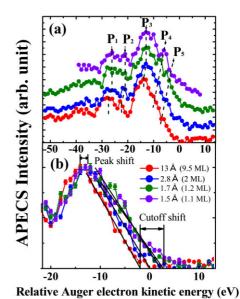


Fig. 2. Si- $L_{23}VV$ -Si-2p APECS of SiO₂/Si(100) with the various thickness.

Figure 2 shows a series of $Si-L_{23}VV-Si^{4+}-2p$ APECS spectra for 13-, 2.8-, 1.7-, and 1.5-Å $SiO_2/Si(100)$. The $Si^{4+}-2p$ *PeKE* positions taken as trigger signals of these APECS were set to the same value. Every wide-scan $Si-L_{23}VV-Si^{4+}-2p$ APECS spectrum in Fig. 2(a) shows clear five peaks (P_1-P_5) . In Fig. 2(b), we show the enlarged $S-L_{23}VV-Si^{4+}-2p$ APECS spectra. The intense peaks shift by ≈ 1 eV to the higher-AeKE side, while the cut-offs shift by ≈ 4 eV to the higher-AeKE side as the SiO_2 thickness decreases. These results indicate that the binding energies of valence band maximum of 1.5- and 1.7-Å $SiO_2/Si(100)$ are shifted upwards by ≈ 1.6 eV (toward the Fermi level) in comparison with that of 13-Å $SiO_2/Si(100)$ [1].

References

[1] T. Kakiuchi et al., J. Phys. Soc. Jpn. in press (2011).

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